

A-20929

PATENT

JC625 U.S. PTO
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02/10/00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Alek C. CHEN
Serial No.: Not yet assigned
Filed: February 10, 2000
For: *In Situ Proximity GAP Monitor for Lithography*

#2
15Sep00
R.Tousi

INFORMATION DISCLOSURE STATEMENT

Box DD
Assistant Commissioner for Patents
Washington, D.C. 20231

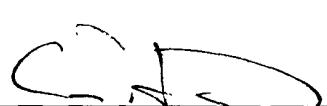
Dear Sir:

In compliance with applicant's duty of disclosure under 37 CFR §1.56, applicant submits the attached Form PTO-1449 listing publications for consideration by the Examiner. Kindly make these publications of record in the file of the application.

The Examiner is respectfully requested to initial a copy of the attached Form PTO-1449 to show consideration of the publications, and to return the initialed form to undersigned counsel.

Respectfully submitted,

Date: 2/10/2000


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